

WEST Search History

DATE: Sunday, March 07, 2004

<u>Hide?</u>	<u>Set Name</u>	<u>Query</u>	<u>Hit Count</u>
		<i>DB=USPT; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L7	438/905.ccls. and remote	33
<input type="checkbox"/>	L6	4088926.pn. or 6271148.pn.	2
<input type="checkbox"/>	L5	L4 not l3	23
<input type="checkbox"/>	L4	l1 and 438/\$.ccls.	27
<input type="checkbox"/>	L3	L1 and (134/\$.ccls. or 438/905.ccls.)	5
<input type="checkbox"/>	L2	L1 and 134/\$.ccls. or 438/905.ccls.	209
<input type="checkbox"/>	L1	conductance and (remote with plasma)	88

END OF SEARCH HISTORY

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		<i>DB=USPT; PLUR=YES; OP=ADJ</i>	
<input type="checkbox"/>	L10	L8 and ((viewport or window) same (input or inlet))	54
<input type="checkbox"/>	L9	L8 and (viewport or window)	346
<input type="checkbox"/>	L8	remote plasma	1039
<input type="checkbox"/>	L7	438/905.ccls. and remote	33
<input type="checkbox"/>	L6	4088926.pn. or 6271148.pn.	2
<input type="checkbox"/>	L5	L4 not l3	23
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<input type="checkbox"/>	L1	conductance and (remote with plasma)	88

END OF SEARCH HISTORY

Day :
 Sunday
 Date:
 3/7/2004
 Time:
 21:37:51


PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = SELBREDE

First Name = STEVEN

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10
<u>60374218</u>	Not Issued	159	04/19/2002	SYSTEM FOR DEPOSITING A THIN FILM ONTO A SUBSTRATE USING A LOW PRESSURE GAS PRECURSOR	SELBREDE, STEVEN C.
<u>60216603</u>	Not Issued	159	07/07/2000	APPARATUS AND METHODS FOR REMOTE PLASMA CLEAN	SELBREDE, STEVEN C
<u>10413507</u>	Not Issued	030	04/14/2003	SYSTEM FOR DEPOSITING A FILM ONTO A SUBSTRATE USING A LOW PRESSURE GAS PRECURSOR	SELBREDE, STEVEN C.
<u>09896283</u>	Not Issued	071	06/29/2001	SYSTEMS AND METHODS FOR REMOTE PLASMA CLEAN	SELBREDE, STEVEN C.
<u>09707368</u>	<u>6551447</u>	150	11/06/2000	INDUCTIVE PLASMA REACTOR	SELBREDE, STEVEN C.
<u>09118281</u>	<u>6143129</u>	150	07/17/1998	INDUCTIVE PLASMA REACTOR	SELBREDE , STEVEN C.
<u>07902995</u>	<u>5447570</u>	150	06/23/1992	PURGE GAS IN WAFER COATING AREA SELECTION	SELBREDE , STEVEN C.
<u>07849488</u>	<u>5383971</u>	150	03/11/1992	DIFFERENTIAL PRESSURE CVD CHUCK	SELBREDE , STEVEN C.

<u>07812734</u>	Not Issued	161	12/23/1991	PURGE GAS IN WAFER COATING AREA SELECTION	SELBREDE , STEVEN C.
<u>07596512</u>	<u>5094885</u>	150	10/12/1990	DIFFERENTIAL PRESSURE CVD CHUCK	SELBREDE , STEVEN C.

Inventor Search Completed: No Records to Display.

Search Another: Inventor

Last Name	First Name
<input type="text" value="SELBREDE"/>	<input type="text" value="STEVEN"/>

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<input type="checkbox"/>	L14	l8 and 'substrates'	955
<input type="checkbox"/>	L13	l8 and (two substrates)	9
<input type="checkbox"/>	L12	L11 and viewport	0
<input type="checkbox"/>	L11	6143129.pn. or 6551447.pn. or 6120610.pn.	3
<input type="checkbox"/>	L10	L8 and ((viewport or window) same (input or inlet))	54
<input type="checkbox"/>	L9	L8 and (viewport or window)	346
<input type="checkbox"/>	L8	remote plasma	1039
<input type="checkbox"/>	L7	438/905.ccls. and remote	33
<input type="checkbox"/>	L6	4088926.pn. or 6271148.pn.	2
<input type="checkbox"/>	L5	L4 not l3	23
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<input type="checkbox"/>	L3	L1 and (134/\$.ccls. or 438/905.ccls.)	5
<input type="checkbox"/>	L2	L1 and 134/\$.ccls. or 438/905.ccls.	209
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